

(E)  
10-301  
7/13

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Masamichi NAKASHIBA et al.

Serial No. 09/589,388

Filed June 8, 2000



Docket No. 2000\_0722

Group Art Unit 3723

Examiner G. Nguyen

APPARATUS FOR AND METHOD FOR  
POLISHING WORKPIECE

THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
FEE FOR THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0975.

AMENDMENT

Assistant Commissioner for Patents,  
Washington, D.C.

Sir:

In response to the Office Action of June 21, 2001, please amend the above-referenced U.S. patent application as follows:

In the Claims:

Please add the following new claims:

*(Handwritten mark: A large arrow pointing down and left, with a small circle and a checkmark inside.)*

73.(NEW) A polishing apparatus for polishing a surface of a workpiece, comprising:  
a top ring for holding a workpiece; and  
a plurality of chambers formed in said top ring, fluid pressures being supplied in said respective chambers to provide polishing pressure to a central area and an outer circumferential area of the workpiece, wherein a radial width of said outer circumferential area is narrower than that of said central area.

RECEIVED  
SEP 25 2001  
TECHNOLOGY CENTER 3700